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in the following listed application(s) or patent(s) for which the issue fee has been paid.

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| 7,402,467B1 | 09/535,233 | 07/22/2008 | 03/24/2000 | 1670 | SEL 171 |

Respectfully Submitted,



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(12) **United States Patent**
Kadono et al.

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| (75) Inventors: Masaya Kadono, Kanagawa (JP); Shunpei Yamazaki, Tokyo (JP); Yukio Yamauchi, Shizuoka (JP); Hidehito Kitakado, Hyogo (JP) | 6,221,766 | B1 * | 4/2001 | Wasserman | 438/656 |
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(Continued)

(5)

(58) **Field of Classification Search** 156/345,
438/151, 704; 204/192.5; 257/1; 65/60.5
See application file for complete search history.

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ABSTRACT

A reduction in contaminating impurities in a TFT, and a TFT which is reliable, is obtained in a semiconductor device which uses the TFT. By removing contaminating impurities residing in a film interface of the TFT using a solution containing fluorine, a reliable TFT can be obtained.

32 Claims, 17 Drawing Sheets

